EAST Search History

Ref #	Hits	Search Query	DBs	Default Operator	Plurals	Time Stamp
L1	2105	382/144-150.ccls.	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2007/05/18 09:11
L2	3575	382/141-150.ccls.	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2007/05/18 09:11
L3	18	382/141-150.ccls. and (threshold near2 region) with defect	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2007/05/18 09:28
L4	17	382/141-150.ccls. and (threshold) with defect with upper with lower	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2007/05/18 09:40
L5	2	("20040150813").PN.	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2007/05/18 10:54
L6	260	automatic adj defect adj classification	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2007/05/18 10:55
L7	84	automatic adj defect adj classification and monitor	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2007/05/18 11:09

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L8	22268	illuminating adj light	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2007/05/18 11:09
L9	264	illuminating adj light with ultra\$violet	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2007/05/18 11:09

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			2. Robustness evaluation of cost-optimum sampling plan for in-line wafer inspection by using Taguchi methods Suzuki, R.; Nakamae, K.; Fujioka, H.; Semiconductor Manufacturing, 2005, ISSM 2005, IEEE International Symposium on 13-15 Sept. 2005 Page(s):386 - 389 Digital Object Identifier 10.1109/ISSM.2005.1513385 AbstractPlus Full Text: PDE(322 KB) IEEE CNF	f cost-optimum sampli Tujioka, H.; 386 - 389 1109/ISSM.2005.151338	pling plan for in-line 5, IEEE International 5 3385 NF	s wafer ins Symposium	pection by
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		"	3. Monitoring and preventing arc-induced wafer damage in 300mm manufacturing Parker, J.; Reath, M.; Krauss, A.F.; Campbell, W.J.; Integrated Circuit Design and Technology, 2004. ICICDT '04. International Conference on 2004 Page(s):131 - 134 Digital Object Identifier 10.1109/ICICDT.2004.1309927	ig arc-induced wafer ss, A.F.; Campbell, W nd Technology, 2004 1109/ICICDT.2004.13	r damage in 300mm J.J.; . ICICDT '04. Internati 809927	manufactı jonal Confe	rring gren <u>œ on</u>

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03/21/2006	<u> </u>	DOCK	CASE DOCKETED TO EXAMINER IN GAU		
02/22/2006		C.ADB	CORRESPONDENCE ADDRESS CHANGE		
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